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(Received...)

Despite the observation by a number of groups of a strong luminescence sensitization effect of erbium ions by excitation exchange from silicon nanoclusters, there is considerable experimental evidence that the fraction of Er ions excited by Si-nc is actually very low for much of the material reported. In this work, we examine the evidence, and point out that Er excited state absorption is the likely cause.

In recent years, silicon nanocluster-sensitized Er-doped materials have generated great interest, as it has been demonstrated that silicon nanoclusters (Si-nc) can transfer their energy very effectively to the Er ions surrounding them. The attraction of this indirect excitation is two-fold: (i) the excitation cross section of the Si-nc is at least four orders of magnitude greater than that of rare-earths in silica, (ii) the broadband absorption spectrum of the Si-nc allows pumping with sources such as LEDs. The latter would dramatically lower the cost of Er-doped amplifiers, and allow pumping geometries such as top-down non-guided pumping, which would enable easy integration of amplifiers in planar optical circuits. However, no lasing action has been achieved to date. Indeed, there is cumulating evidence that, for much of the material that has been reported, the fraction of Er ions that can be excited by Si-nc is actually very low - of the order of a few percent or less. Clearly, this issue will need to be understood and resolved in order for viable lasers and amplifiers to be realized from this material system.

There is now documented evidence from multiple groups, although it may not always have been explicitly recognized, that the fraction of Er ions that are excitable by Si ncs is often quite low^{1,2}. For example, for the data presented by Fujii et al¹, the Er PL (photoluminescence) for two samples with the same Er concentration, one of which contained Si nc (SRO) and the other without (SiO₂), was reported to differ by a factor of 30 under the same pumping conditions (see Fig. 1). It is straightforward to show by rate equation analysis that the Er excited state populations are given by:

$$N_{2}^{SiO_{2}} = \frac{\sigma \tau P N_{Er}}{1 + \sigma \tau P}; \quad N_{2}^{SRO} = \frac{k \tau n_{b} N_{Er}}{1 + k \tau n_{b}}$$
(1)

where σ is the Er pump absorption cross section, τ the Er luminescence lifetime, *P* the pump flux, N_{Er} the Er ion concentration, *k* the Si-nc to Er excitation transfer coefficient, and n_b is the Si nc excited state population.



Fig. 1 Er PL data for Er-doped SRO and Er-doped SiO_2 extracted from Ref. 1. The PL intensity differed by only a factor of 30 at maximum pump power, in contrast to an expected ratio of 2 000 if all the Er ions in the SRO sample had been excited.

At the maximum pump power reported (1.5W/cm^2) , the SRO sample is in the saturation regime while the SiO₂ sample is still in the linear regime; therefore the ratio of the number of excited Er ions in the two samples can be simply estimated as:

$$\frac{N_2^{SRO}}{N_2^{SiO_2}} \cong \frac{1}{\sigma \tau P}$$
(2)

Taking $\sigma_{488nm} \sim 10^{-20}$ cm², $\tau = 10$ ms and $P=4x10^{18}$ cm²s⁻¹ (corresponding to 1.5W/cm²), this yields an Er concentration ratio of 2 000. As the experimentally observed PL ratio is only 30, this indicates that just 1.5% of the available Er ions in the SRO sample have been excited. This conclusion seems surprising considering that, for the volume fraction of Si nc and Er concentration specified in the SRO sample, the majority of the Er ions would be expected lie in the vicinity (within 1.5nm, the interaction range for Si nc-to-Er energy transfer³) of a Si-nc. Nonetheless, the small percentage inferred above is consistent with the findings of Wojdak et al,²

as they report a sublinear behavior beyond an excited Er population of 1.1×10^{18} out of 2.2×10^{20} cm⁻³, as estimated from their cw pumping data.

In fact, the small fraction of Er ions that is excited by the Si nc is related to a previous debate on whether a Si nanocrystal can excite more than one Er ion^{4,5}. Initial evidence seemed to suggest that each Si nanocrystal could only excite one Er ion, leading to various hypotheses such as Auger de-excitation and pair-induced quenching to account for this limit⁴. It is now becoming clear though that multiple Er ions (as many as 20) can be excited if the pump power is increased sufficiently - by 10-100 times beyond the saturation power². More recently, the framing of this problem has become complicated by findings that strong Er PL can be sensitized not just with Si nanocrystals, but also by an amorphous silicon network in which no distinct Si nanocrystals exist⁶.

To date, no compelling explanation has been able to account satisfactorily for all these observations in a consistent manner. For example, a plausible explanation that most (over 90%) of the Er ions in the material may be optically inactive or quenched, and therefore non-luminescent, appears at odds with the ability of these ions to be excited at high power, after the initial Er PL saturation has occurred. Furthermore, the Er ions that are not excited by the Si-nc can nonetheless be excited by direct resonant optical excitation, which provides further proof that these Er ions are optically active, though not susceptible to excitation exchange from Si-ncs. Fig. 2 shows the Er PL for a sample grown at UCL by plasma-enhanced chemical vapor deposition,⁷ under 476nm (non-resonant) and 488nm (resonant) pumping. We see that the Er PL under 488nm pumping is almost twice as strong as with 476nm pumping at maximum pump power, suggesting that the Er ions excited directly by the optical pump are equal in number to those excited by the Si-nc. This is supported by the dashed curve, which we have constructed simply by adding a linear contribution to the Er PL curve under 476nm pumping (the numbers of Er ions excited directly by the 488nm pump should increase linearly with pump power at these power levels). From these curves, we can also estimate the fraction of Er ions excited by Si nc as the Er PL saturates: it comes out to just 0.7% - similar to the samples studied by Fujii et al^1 and Wojdak et al.²

The low fraction of Er ions excitable by Si-ncs is clearly a pressing issue with crucial device implications, especially since the unexcited Er ions still exhibit their characteristic absorption, and will contribute to a large loss⁴. In a recent paper, we pointed out the existence of Er excited state absorption (ESA) occurring in this material system⁸. We propose here that ESA is the primary cause for the low fraction of Er ions excited by the Si-nc.

ESA occurs when a nanocluster transfers its energy to an excited Er ion, elevating it from the ${}^{4}I_{13/2}$ to the ${}^{2}H_{11/2}$ or ${}^{4}S_{3/2}$ levels. The excited erbium ion then rapidly decays back to the ${}^{4}I_{13/2}$ level, and the net result is just an energy loss. To understand the impact of ESA on the fraction of Er ions excited, let us consider the situation in which there are

multiple Er ions surrounding each nanocrystal. Even if all these ions are within the excitation range of the Si nc, the Si nc will predominantly transfer its energy to the nearest Er ion due to the short-range nature of the Si nc-Er interaction, which falls off rapidly with distance³. Because the lifetimes of the ²H_{11/2} or ⁴S_{3/2} levels are much shorter than that of the ⁴I_{13/2} level, any further transfer of energy from the Si nc – preferentially to the same ion – will result in a cycling of the Er ion between the ⁴I_{13/2} and ²H_{11/2} or ⁴S_{3/2} levels.



Fig. 2: (Color online) Left axis: Er PL behaviour for 476nm and 488nm optical pumping. The dashed line is the PL curve under 476nm pumping with a linear component added on to it. Right axis: Si-nc PL intensity at 1.6 eV. The sample contains 7 at. % excess Si and 1 at. % Er.

To study this effect, we have run simulations of various Si-nc and Er populations, based on rate equation analyses assuming each nanocluster is surrounded by a set of Er ions, which are located randomly. Although the exact nature of the interaction between the Si-nc and the Er ions is still under debate (whether it is a dipole-dipole or Auger interaction), we assume (without much loss of generality to the argument here) a dipole-dipole interaction process. The energy transfer probability then diminishes as the sixth power of the Si nc-Er separation distance. The separation distance is taken from the Er ion to the surface of the nanocluster, rather than to the core, because the surface states have been shown to play a crucial role in the emission process at 800nm^{9,10}. The minimum distance of Er ions to a nanocluster was set to 0.16 nm, the length of the Si-O bond. Back-transfer and Auger processes from the Er to the Si-nc were neglected, as it has been experimentally shown that they are unlikely to occur for this material.¹¹ For simplicity, and in keeping with results from our previous analysis of ESA in this system⁸, the ESA coupling coefficient is taken to be comparable (equal) to the Si nc-Er ground state coupling coefficient. We performed the calculations with ESA present, and without ESA for comparison.

We first consider the case similar to that studied by Wojdak et al^2 , in which there were 220 Er ions per nanocluster. Using the parameters specified in that paper, we calculated the ratio

of excited Er ions and nanoclusters versus pump photon flux. In that paper, the excited population was measured experimentally, enabling us to compare our results with the measurements. The result is shown in Fig. 3a.

The saturation behavior of the Er is markedly different when ESA is present. At very low flux, the excited Er population grows linearly. When the excited population reaches ~0.5%, the behavior becomes sublinear. This threshold population corresponds to the situation of one excited Er per nanocluster, and shows that it is considerably more difficult to excite the second nearest Er ion. This effect does not occur if ESA is absent (dashed line). Considering the simplicity of the model (which neglects concentration quenching or up-conversion effects), and the fact that the only free parameter is the Si nc-Er coupling constant, there is very good qualitative agreement with the experimental behavior observed in Ref. 2, strongly suggesting that ESA is responsible for this sublinear, gradual saturation behavior.



Fig. 3: (Color online) Excited population versus pump photon flux calculated from our model. (a) Considering the parameters extracted from Ref. 2 ([Si-nc]= 10^{18} cm⁻³, [Er]= 2.2×10^{20} cm⁻³). The void circles represent the Er excited ratio extracted from Fig. 3b of the same paper. (b) Considering one Er per nanocluster, with a concentration of 10^{19} cm⁻³.

The behavior of the Si-nc excited population is also interesting, and informative. If ESA is neglected, the Si nc excited ratio increases nonlinearly when the Er begins to saturate, as depicted in Fig 3a. The physical basis behind this is simple: without ESA, saturation of the Er implies that energy transfer from the Si nc to the Er effectively ceases, or slows to a very low rate constrained by the long (ms) Er lifetime. With this energy dissipation route terminated, the Si nc excited population (and corresponding PL) must therefore increase. By contrast, with ESA occurring, the Si nc excited ratio remains linear with pump power near the Er saturation point. Experimental evidence reported indicates that the Si nc PL is quite linear with pump power as the Er PL saturates¹², which is also confirmed in Fig. 2. This linear Si nc PL behavior can be interpreted as further evidence of ESA occurring in the material.

Finally, we consider the situation where there is at most one Er ion per nanocluster. The material studied by Lee et al¹³ appears to correspond more closely to this situation. Their low Er concentration, together with the low annealing temperature and short annealing time, leads to a high quantity of small Si nanoclusters. For our calculations, we assume concentrations of 10^{19} cm⁻³ for both Si nanoclusters and Er ions, and nanocluster sizes of 1nm, which corresponds roughly to 1 at.% Si excess and 0.05 at.% Er concentration. The results are shown in Fig. 3b.

In this case, the behavior of the system is quite similar whether ESA is present or absent. The entire erbium population can be saturated much more easily at lower pump powers because there is only one Er per Si-nc to excite. It is worth noting that the only report of optical gain has been with such material¹³. However, even though it is easier to achieve a population inversion in this case, ESA will still adversely impact the performance of the optical amplifier or laser, as it represents a constant drain of energy that increases the pump threshold and decreases the slope efficiency.

In conclusion, we have shown that the low fraction of Er ions excitable by Si nc is mainly due to Er excited state absorption in the material. The evidence is manifested in the sublinear behavior of the Er PL signal with pump power, and also the *linear* behavior of the emission coming from the Si nanoclusters. Our model shows good agreement with the experimental behavior reported from multiple groups. Eliminating the excited state absorption, e.g. by further engineering the Si-nc band structure away from the 1.6eV energy transition, should enable multiple Er ions to be readily excited, and at the same time eradicate a highly problematic energy dissipation mechanism. This should enable efficient optical amplifiers and lasers to be realizable in this highly promising material system.

The authors gratefully acknowledge funding support by the Engineering and Physical Sciences Research Council (UK) for this work.

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